



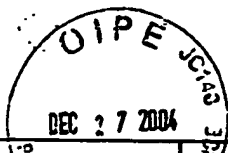
FORM PTO-1449/A and B (Modified)				APPLICATION NO.: 09/975,169	ATTY. DOCKET NO.: P0743/7001
<b>INFORMATION DISCLOSURE STATEMENT BY APPLICANT</b>				FILING DATE: October 11, 2001	
				APPLICANT: Erik Deutsch et al.	
				GROUP ART UNIT: 2872	EXAMINER: Not Yet Assigned
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<i>[Signature]</i>		EP	1 122 577 A2			08-08-2001	
<i>[Signature]</i>		EP	1 143 287 A2			10-10-2001	

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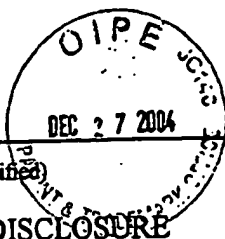
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<i>[Signature]</i>		<u>ANALYSIS OF GRATING LIGHT VALVES WITH PARTIAL SURFACE ELECTRODES</u> , FURLANI et al., J. Appl. Phys. 83 (2), 01/15/98, American Institute of Physics, pp 629-634	

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		5,905,571		Butler et al.	05/18/99
		5,933,277		Troxell et al.	08/03/99
		5,949,568		Koo et al.	09/07/99
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CPL		WO	01/42825	A1	Gutin	06/14/01		
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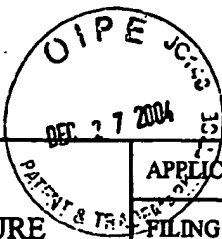
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CPL		<u>POSITIONING, CONTROL, AND DYNAMICS OF ELECTROSTATIC ACTUATORS FOR USE IN OPTICAL AND RF SYSTEMS</u> , E.S. HUNG, 08/21/98 thesis Massachusetts Institute of Technology, 107 pages	
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		<u>MICROMECHANICAL LIGHT MODULATOR ARRAY FABRICATED ON SILICON</u> , K.E. PETERSEN, IBM Research Lab., Applied Physics Letters, Vol. 31, No. 8, 10/15/77, pp 521-523	
CPL		<u>LEVERAGED BENDING FOR FULL-GAP POSITIONING WITH ELECTROSTATIC ACTUATION</u> , E.S. HUNG et al., MIT, Solid-State Sensor and Actuator Workshop Hilton Head Island, SC 06/08/98-06/11/98 pp 83-86	

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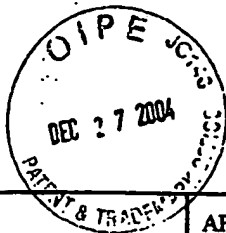
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		<u>MEMS DEFORMABLE MIRRORS FOR ADAPTIVE OPTICS</u> , BIFANO, et al., Dept. of Aerospace and Mech. Eng., BU, Boston, MA, Solid-State Sensor and Actuator Workshop Hilton Head Island, SC 06/08/98- 06/11/98 pp 71-74	
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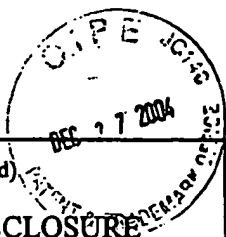
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gpc		<u>INVESTIGATION OF THE MAXIMUM OPTICAL POWER RATING FOR A MICRO-ELECTRO-MECHANICAL DEVICE</u> , BURNS et al., Internat'l Conf. On Solid-State Sensors and Actuators 06/16/97-06/19/97, pp 335-338	

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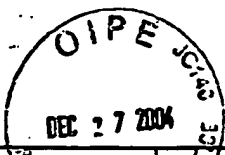
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		APPLICANT: Erik R. Deutsch et al.			
		GROUP ART UNIT: 2872		EXAMINER:	
Sheet	6	of	6		

## U.S. PATENT DOCUMENTS

Examiner's Initials #	Cite No.	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication or of issue of Cited Document MM-DD-YY
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## FOREIGN PATENT DOCUMENTS

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## OTHER ART -- NON PATENT LITERATURE DOCUMENTS

Examiner's Initials #	Cite No.	Include name of the author (in CAPITAL LETTERS) title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, relevant page(s), volume-issue number(s), publisher, city and/or country where published.	Translation (Y/N)	
apl		<u>SYNTHETIC SPECTRA: A TOOL FOR CORRELATION SPECTROSCOPY</u> , SINCLAIR et al., Applied Optics, Vol. 36, No. 15 05/20/97, pp 3342-3348		
		<u>SYNTHETIC INFRARED SPECTRA</u> , SINCLAIR et al., Optical Society of America, Optical Letters, vol. 22, No. 13 07/01/97, pp 1036-1038		
		<u>THE POLYCHROMATOR: A MEMS CORRELATION SPECTROMETER</u> , HUNG et al., Microsystems Technology Laboratories Annual Report 1998,		
		<u>MEMS: RESEARCH AND APPLICATIONS IN MICROELECTROMECHANICAL SYSTEMS</u> , HUNG et al., Poster Session Guidebook, 03/31/98, pp 1 and 4		
apl		<u>EXTENDING THE TRAVEL RANGE OF ANALOG-TUNED ELECTROSTATIC ACTUATORS</u> , HUNG et al., IEEE J. of Microelectromechanical Systems, vol. 8, No. 4, December 1999, pp497-505		

EXAMINER <i>Cherry</i>	DATE CONSIDERED <i>2/21/05</i>
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